

2862



F-6971

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

#7/Amend A  
7/12/03  
C. Per

Applicant : Seiichi HAYASHI, et al.  
Serial No. : 09/852,111  
Filed : May 9, 2001  
For : METHOD AND APPARATUS FOR MEASURING  
THIN FILM, AND THIN FILM DEPOSITION  
SYSTEM  
Group Art Unit : 2882  
Examiner : Hoon K. Song

Certificate of Mailing Under 37 CFR 1.8

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(Name)

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(Signature)

AMENDMENT

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

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Sir:

In response to the Office Action of December 24, 2002, please amend the

above-identified patent application as follows:

07/14/2003 (PARIS) 0000007 101250 09852111  
01 FC:1050 100.00 DA